

**AMENDMENTS TO THE SPECIFICATION**

Please replace the paragraph starting on page 1, line 11, with the following paragraph:

A number of different applications of catadioptric imaging systems for far-field and near-field interferometric confocal microscopy have been described such as in U.S. Patent Applications No. 10/028,508, filed December 20, 2001 [ZI-38], and No. 10/366,651, filed February 3, 2003 [ZI-43] entitled "Catoptric And Catadioptric Imaging Systems;" U.S. Provisional Patent Application No. 60/447,254, filed February 13, 2003 and U.S. Patent Application No. 10/778,371, filed February 13, 2004 [ZI-40] both entitled "Transverse Differential Interferometric Confocal Microscopy," U.S. Provisional Patent Application No. 60/448,360, filed February 19, 2003 and U.S. Patent Application No. 10/782,057, filed February 19, 2004 [ZI-41] both entitled "Longitudinal Differential Interferometric Confocal Microscopy for Surface Profiling;" U.S. Provisional Patent Application No. 60/448,250 and U.S. Patent Application No. 10/782,058, filed February 19, 2004 [ZI-42] both entitled "Method and Apparatus for Dark Field Interferometric Confocal Microscopy;" U.S. Provisional Patent Application No. 60/442,982, filed January 28, 2003 and U.S. Patent Application No. 10/765,229, filed January 27, 2004 [ZI-45] both entitled "Interferometric Confocal Microscopy Incorporating Pinhole Array Beam-Splitter;" and U.S. Provisional Application No. 60/459,425, filed April 1, 2003 and U.S. Patent Application No. [\_\_\_\_] 10/816,180, filed April 1, 2004 [ZI-50] both entitled "Joint Measurement Of Fields Of Orthogonally Polarized Beams Scattered/Reflected By An Object In Interferometry." The above-mentioned patent applications and provisional patent applications are all by Henry A. Hill and the contents are incorporated herein by reference in their entirety.